

RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2624

PATENT APPLICATION  
Docket No.: 2522-047  
Client Ref. No. AW8085US/EK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Deok-Yong KIM

Serial No.: 10/749,670

Examiner: Dennis ROSARIO

Filed: December 30, 2003

Art Unit: 2624

Confirmation No.: 9761

For: METHOD AND APPARATUS FOR DETECTING DEFECTS ON A  
WAFER

Date: November 27, 2007

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116**

Responsive to the Final Office Action, Paper No. 20071004, dated October 15, 2007,  
please amend the application as follows.

- **Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.
- **Remarks/Arguments** begin on page 6 of this paper.